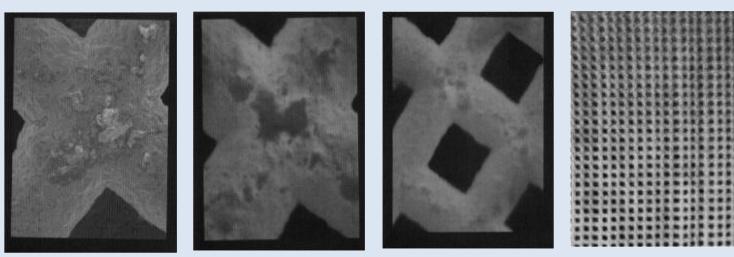




Electron optical column for surface analyses and measurements

Features

- Low energy electron source
- Large current density
- Mountable on CF114
- Bakable
- Small size (beam path ~ 100mm)
- Isolation valve built in



SEM images of Cu 400 mesh (L&S:32μm)

Specifications

Acceleration voltage V_A	~5000V		
Probe current I_p	$3 \times 10^{-12} \sim 10^{-8} A$		
Minimum probe size	$\sim 10\text{nm}$ ($V_A = 5000V$, $I_p = 2 \times 10^{-10}A$, WD = 6mm)		
Specimen Chamber	$< 2 \times 10^{-3}\text{Pa}$		
Bakable	$\sim 150^\circ\text{C}$		
Base Flange	CF114		
Weight	~20kg		
Con-Struc-tions	Gun	ZrO/W emitter	
		Control lens	
		SIP (20ℓ/s)	
		Isolation valve	
	Blanker	Electrostatic quadrupole	
	Aligner	Electrostatic octupole	
	Deflector	Double electrostatic octupole	
	Objective lens	electrostatic	

* Specifications are subjected to change without notice.

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